

**REPLY UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP ART UNIT 2818**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s) : LAERMER et al.  
Serial No. : 10/524,610  
Filed : August 11, 2005  
For : LAYER SYSTEM HAVING A SILICON LAYER AND A  
PASSIVATION LAYER, METHOD FOR CREATING A  
PASSIVATION LAYER ON A SILICON LAYER AND ITS USE  
Art Unit : 2818  
Examiner : HO, Hoang Quan Tran  
Confirmation No. : 9981

I hereby certify that this correspondence is being electronically  
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**REPLY UNDER 37 C.F.R. § 1.116**

S I R:

This paper is filed in response to the Final Office Action dated October 9, 2007 in  
connection with the above-captioned application.

**Remarks** begin on page 2 of this paper.